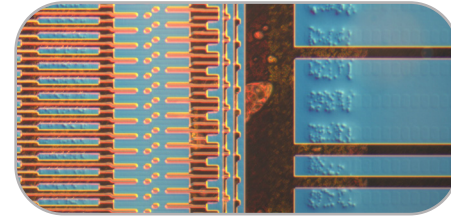
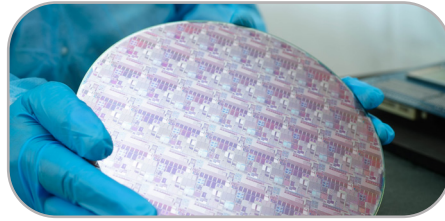
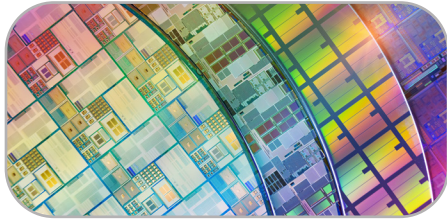


UNITRON's WXS-800 Wafer Inspection Microscope delivers high efficiency, reliability and easy operation for semiconductor defect inspection.



Wafer
Inspection
Microscope
CAT# 15100



The WXS-800 Wafer Inspection Microscope is designed for brightfield, darkfield and simple polarization observation (optional DIC).

The large stage accommodates 8" wafers and flat panel displays.

Ergonomic trinocular head delivers true-to-sample images with low-position controls for lasting comfort.



◀ Double layer mechanical stage with 14"x12" platform has a 210mmx210mm movement range, sample holder for 8" wafers, XY stage control, and a mechanical clutch for coarse stage positioning

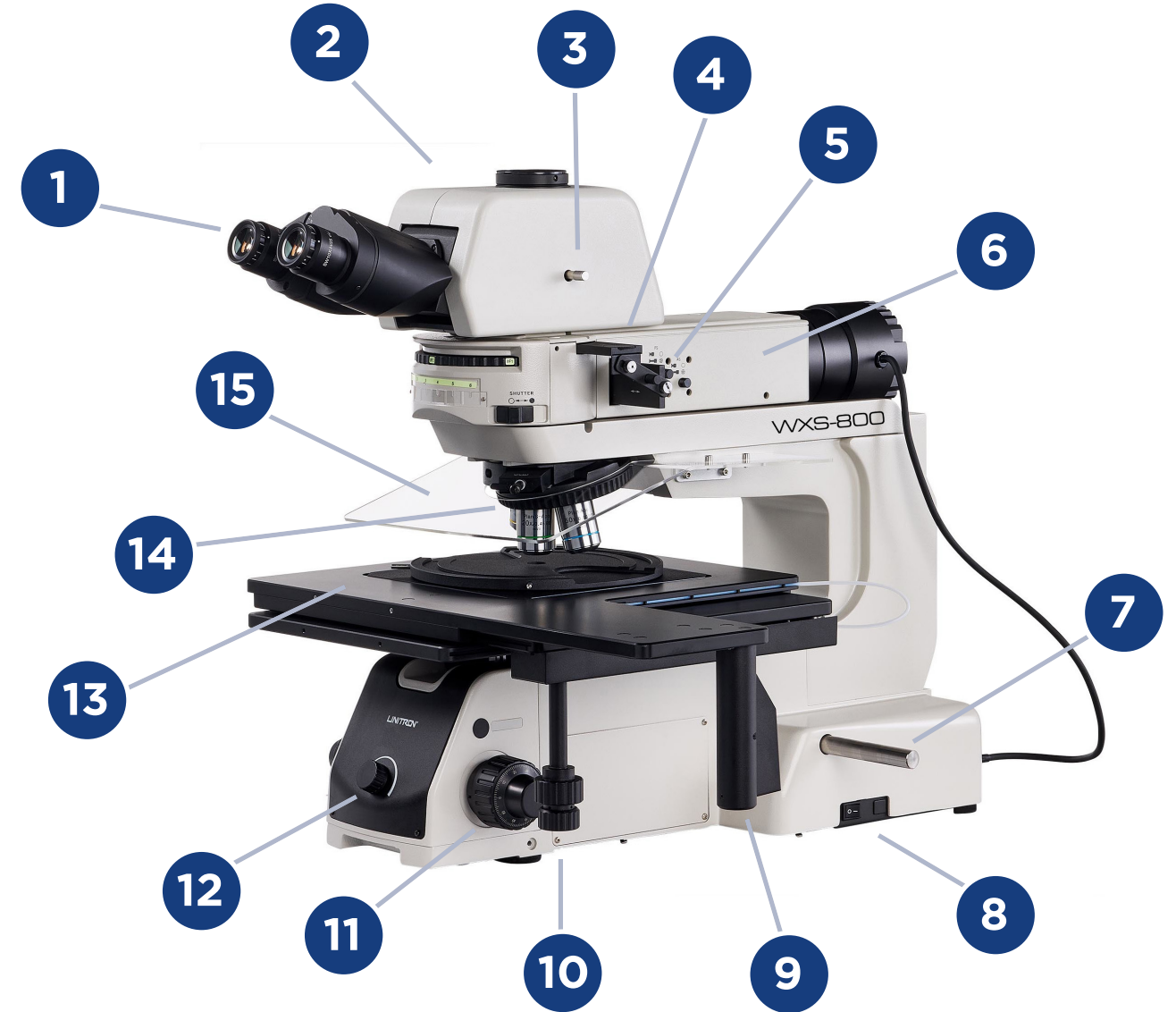
▶ Ergonomic trinocular viewing head with erect image, 0-30° binocular tube tilting with 100/0 : 0/100 light path selector

◀ Yellow, blue, green and frosted filters also come standard with the WXS-800



Digital cameras can be easily connected to the WXS-800 providing rapid image acquisition and processing, and sample documentation. Engineered for brightfield, darkfield and simple polarized light observation, the WXS-800 delivers professional features at an affordable price, in an easy-to-use ergonomic design.

Key Features



- | | |
|--|---|
| <ol style="list-style-type: none"> 1. SW10x-25mm focusing eyepieces 2. Ergonomic trinocular viewing head with imaging port 3. Light path selector 100/0 : 0/100 4. Slider with rotatable analyzer 5. Polarizer slider 6. Reflected light illuminator, condenser with aperture diaphragm, 3-position turret, filter slots 7. Carry handle (on both sides; alternate storage positions on back) | <ol style="list-style-type: none"> 8. Power switch 9. Mechanical clutch for coarse stage positioning 10. X-Y stage control 11. Low position coaxial coarse/fine focus 12. Variable light intensity adjustment 13. Double layer mechanical stage 14. Encoded sextuple nosespiece with DIC slot 15. Anti-static dust shield |
|--|---|

Specifications

Optical System	Infinity optical system, f = 200mm
Observation Method	Brightfield and simple polarizer/analyzer 360° rotating; blue, green and frosted filters
Viewing Head	Ergonomic trinocular viewing head with erect image 0-30° binocular tube tilting 100/0 : 0/100 light path selector Interpupillary distance adjustment 47-78mm
Eyepieces	SW10X-H25mm, focusing
Objectives	Plan semi-Apochromatic 5x (NA 0.15), 10x (NA 0.3), 20x (NA 0.4), 50x (NA 0.8), Brightfield/Darkfield objectives <i>Optional 100x (NA 0.9)</i>
Nosepiece	Encoded sextuple nosepiece for brightfield and darkfield objectives, DIC slot
Stage	Double layer mechanical stage; 14" x 12" platform; 210mm x 210mm movement range; sample holder for 8" wafers; XY stage stalk; mechanical clutch for course stage positioning
Illumination	Reflected light illuminator, NA 0.65 condenser with centerable aperture diaphragm and field diaphragm (Köhler alignment); 3-position turret (Brightfield, Brightfield+ND6, Darkfield positions); 5W LED with variable intensity adjustment and Light Intensity Memory (LIM) function; two filter slots
Contrast Methods (All reflected)	Brightfield, Darkfield, Simple Polarization, Differential Interference Contrast (optional); blue, green, yellow and frosted filter sliders included
Focusing	Low position coaxial coarse/fine focus; focus travel limit; 33mm focusing range; 1µm fine focus indication
Optional Accessories	Digital cameras and camera adapters; DIC slider and prisms; Reticles; Stage micrometers
Warranty	5 year limited warranty for parts and labor; 1 year warranty on electronic components and LED bulb

Dimensional Drawings (in mm)

